Teodor Gotszalk

List of Publications by Year in descending order

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1040056 996975 38 278 9 15 citations h-index g-index papers 38 38 38 376 docs citations times ranked citing authors all docs

#	Article	IF	CITATIONS
1	Photon force microelectromechanical system cantilever combined with a fibre optic system as a measurement technique for optomechanical studies. Measurement Science and Technology, 2022, 33, 027001.	2.6	2
2	Influence of B/N co-doping on electrical and photoluminescence properties of CVD grown homoepitaxial diamond films. Nanotechnology, 2022, 33, 125603.	2.6	5
3	MEMS displacement generator for atomic force microscopy metrology. Measurement Science and Technology, 2021, 32, 065903.	2.6	2
4	Stable Field Electron Emission and Plasma Illumination from Boron and Nitrogen Coâ€Doped Edgeâ€Rich Diamondâ€Enhanced Carbon Nanowalls. Advanced Materials Interfaces, 2021, 8, 2100464.	3.7	9
5	Quartz tuning fork mass change sensing for FIB/SEM technology. Micron, 2020, 129, 102792.	2.2	O
6	Origin and anomalous behavior of dominant defects in 4H-SiC studied by conventional and Laplace deep level transient spectroscopy. Journal of Applied Physics, 2020, 127, .	2.5	7
7	Analysis of the electrolytically polished skeletal dentures surfaces using various nano- and microscopic technologies. Acta of Bioengineering and Biomechanics, 2019, 21, 123-129.	0.4	O
8	Metrological 2iOF fibre-optic system for position and displacement measurement with 31 pm resolution. Review of Scientific Instruments, 2018, 89, 045001.	1.3	1
9	Contact atomic force microscopy using piezoresistive cantilevers in load force modulation mode. Ultramicroscopy, 2018, 184, 199-208.	1.9	9
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10	Force Spectroscopy with Quantitative On-Cantilever Force Control. Proceedings (mdpi), 2018, 2, 915.	0.2	2
10	Force Spectroscopy with Quantitative On-Cantilever Force Control. Proceedings (mdpi), 2018, 2, 915. Mechanical Impedance Analysis of a Novel MEMS Photon Force Sensor. Proceedings (mdpi), 2018, 2, 921.	0.2	1
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11	Mechanical Impedance Analysis of a Novel MEMS Photon Force Sensor. Proceedings (mdpi), 2018, 2, 921. New design of the cantilevers for radiation pressure investigations. Microelectronic Engineering,	0.2	1
11 12	Mechanical Impedance Analysis of a Novel MEMS Photon Force Sensor. Proceedings (mdpi), 2018, 2, 921. New design of the cantilevers for radiation pressure investigations. Microelectronic Engineering, 2018, 201, 10-15. Electromagnetic cantilever reference for the calibration of optical nanodisplacement systems.	2.4	7
11 12 13	Mechanical Impedance Analysis of a Novel MEMS Photon Force Sensor. Proceedings (mdpi), 2018, 2, 921. New design of the cantilevers for radiation pressure investigations. Microelectronic Engineering, 2018, 201, 10-15. Electromagnetic cantilever reference for the calibration of optical nanodisplacement systems. Sensors and Actuators A: Physical, 2018, 282, 149-156. Multifrequency Kelvin probe force microscopy on self assembled molecular layers and quantitative	0.2 2.4 4.1	7
11 12 13	Mechanical Impedance Analysis of a Novel MEMS Photon Force Sensor. Proceedings (mdpi), 2018, 2, 921. New design of the cantilevers for radiation pressure investigations. Microelectronic Engineering, 2018, 201, 10-15. Electromagnetic cantilever reference for the calibration of optical nanodisplacement systems. Sensors and Actuators A: Physical, 2018, 282, 149-156. Multifrequency Kelvin probe force microscopy on self assembled molecular layers and quantitative assessment of images' quality. Ultramicroscopy, 2018, 194, 100-107.	0.2 2.4 4.1 1.9	1 7 9 2
11 12 13 14	Mechanical Impedance Analysis of a Novel MEMS Photon Force Sensor. Proceedings (mdpi), 2018, 2, 921. New design of the cantilevers for radiation pressure investigations. Microelectronic Engineering, 2018, 201, 10-15. Electromagnetic cantilever reference for the calibration of optical nanodisplacement systems. Sensors and Actuators A: Physical, 2018, 282, 149-156. Multifrequency Kelvin probe force microscopy on self assembled molecular layers and quantitative assessment of images' quality. Ultramicroscopy, 2018, 194, 100-107. Optimal Design of Electromagnetically Actuated MEMS Cantilevers. Sensors, 2018, 18, 2533.	0.2 2.4 4.1 1.9	1 7 9 2

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19	Light Extraction From Scintillating Crystals Enhanced by Photonic Crystal Structures Patterned by Focused Ion Beam. IEEE Transactions on Nuclear Science, 2016, 63, 644-648.	2.0	6
20	FAPA mass spectrometry of designer drugs. Talanta, 2016, 146, 29-33.	5.5	14
21	Selfâ€supporting graphene films and their applications. IET Circuits, Devices and Systems, 2015, 9, 420-427.	1.4	9
22	Electrochemical generation of selegiline metabolites coupled to mass spectrometry. Journal of Chromatography A, 2015, 1389, 96-103.	3.7	13
23	Carrier density distribution in silicon nanowires investigated by scanning thermal microscopy and Kelvin probe force microscopy. Micron, 2015, 79, 93-100.	2.2	6
24	Heat assisted sample introduction and determination of cannabinoids by dielectric barrier discharge ionization mass spectrometry. International Journal of Mass Spectrometry, 2015, 386, 32-36.	1.5	10
25	Scanning probe microscopy investigations of the electrical properties of chemical vapor deposited graphene grown on a 6H-SiC substrate. Micron, 2015, 68, 17-22.	2.2	11
26	Dielectric Barrier Discharge Ionization in Characterization of Organic Compounds Separated on Thin-Layer Chromatography Plates. PLoS ONE, 2014, 9, e106088.	2.5	20
27	Piezoresistive cantilever working in a shear force mode forin situcharacterization of exposed microand nanostructures. Measurement Science and Technology, 2014, 25, 044018.	2.6	7
28	Quality factor and resonant frequency measurement by ARMA process identification of randomly excited MEMS/NEMS cantilever. , 2014, , .		0
29	Application of quartz tuning forks for detection of endotoxins and Gram-negative bacterial cells by monitoring of Limulus Amebocyte Lysate coagulation. Biosensors and Bioelectronics, 2014, 58, 132-137.	10.1	18
30	Investigations of mechanical properties of microfabricated resonators using atomic force microscopy related techniques. Microelectronic Engineering, 2014, 119, 164-168.	2.4	5
31	Investigation of multi-junction solar cells using electrostatic force microscopy methods. Ultramicroscopy, 2014, 141, 1-8.	1.9	13
32	Investigation of thermal effects in through-silicon vias using scanning thermal microscopy. Micron, 2014, 66, 63-68.	2.2	7
33	Efficient broken line fitting procedure for analysis of force spectroscopy curves in chemical force microscopy. Journal of Applied Physics, 2013, 114, 064310.	2.5	0
34	Focused ion beam milling and deposition techniques in validation of mass change value and position determination method for micro and nanomechanical sensors. Journal of Applied Physics, 2012, 112, .	2.5	7
35	Fabrication and metrology of electromagnetically actuated microcantilever arrays for biochemical sensing., 2012,,.		1
36	Modification and Characterization of Metallized Tips for Scanning Probe Microscopy. Praktische Metallographie/Practical Metallography, 2007, 44, 451-463.	0.3	1

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#	Article	IF	CITATIONS
37	Combined Shear Force-Tunneling Microscope with Interferometric Tip Oscillation Detection for Local Surface Investigation and Oxidation., 2006, , 144-156.		3
38	Calibration and examination of piezoresistive Wheatstone bridge cantilevers for scanning probe microscopy. Ultramicroscopy, 2003, 97, 385-389.	1.9	30